

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Stefan Peter Hau-Riege

Docket No.: IL-11154

Serial No.:

Group Art Unit:

Filed :

Examiner:

For : Method For Characterizing Mask Defects Using
Image Reconstruction From X-Ray Diffraction Patterns

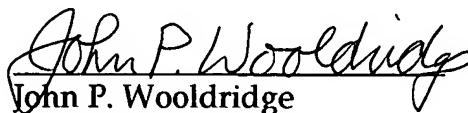
INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Forwarded herewith is an Information Disclosure Statement, Form-1449, in
the above-identified application. A copy of the cited references are enclosed.

Respectfully submitted,


John P. Wooldridge
Agent for Applicants
Registration No. 38,725

Dated: February 20, 2004

Enclosure:

As noted above

[illegible]